

WHAT IS CLAIMED IS:

1. A scanning electron microscope for detecting a pattern on the basis of electrons obtained by scanning an electron beam on a sample and identifying a desired position on the basis of said detected pattern and a pattern registered beforehand, wherein:

said microscope has means for setting information concerning a pattern kind, an interval between a plurality of parts constituting said pattern, and a size of parts constituting said pattern and

means for forming a pattern image composed of a plurality of parts on the basis of said information obtained by said means.